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Covid-19



JCK2020_Registration

• Please registration by December 9

Organized by

- Korea Institute of Industrial Technology
- Korea Institute of Machinery & Materials
- Device Technology Research Institute/ AIST
- International Joint Laboratory for Micro/ Nano Manufacturing and Measurement Technology/Xi'an Jiaotong University

Conference Site

<https://zoom.us>

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The 11th Japan-China-Korea Conference on MEMS/NEMS (JCK MEMS/NEMS 2020)

Dec. 10, 2020 Online, Korea

The 11th Japan-China-Korea Joint Conference on MEMS/NEMS (JCK MEMS/NEMS 2020), is organized to provide an annual East Asian forum for the recent progress in MEMS/NEMS technology with a special East Asia issues and collaboration through JCK networking.

Since 1st JCK MEMS/NEMS Conference was held at Sapporo, Japan, 2010, JCK MEMS/NEMS conference is opening at JCK countries every year.

The 10th JCK MEMS/NEMS 2019 was held at Crystal Hall, Asahikawa, Japan.

Due to COVID 19, 11th JCK MEMS/NEMS conference will be held as on-line seminar hosted by Korea, December 10, 2020.

This conference has composed some special programs with plenary session, invited session, and on-line banquet each JCK countries.

We are looking forward to visit the On-line JCK MEMS/NEMS 2020, discuss friendly and share ideas with all members.

Important Dates

Author Notification : **Wednesday, November 25**

Please registration by December 9

Topics and Scope

- Micro/Nano Fabrication Technology
- Micro/Nano Electronics & Flexible Electronics
- Micro/Nano Sensors & Actuators
- Micro/Nano systems
- Additive Manufacturing Technology
- Networked Microsystems & IoT Technology
- Material & Characterization
- Integration & Packaging Technology
- Modeling & Simulation of Manufacturing Process
- Others

Committee

Conference General Chair

SungHo LEE
(Korea Institute of Industrial & Technology, Korea)

Conference Co- Chair

Sang-Seok Lee
(Tottori University, Japan)
Zhao Libo
(Xi'an Jiaotong University, China)

JCK MEMS/NEMS 2020

Date: 10th December 2020, P.M 14:00 - 18:30

Web conference and local meetings at Seoul, Odaiba and Xi'an

General Chair Sung-ho Lee at KITECH, Korea

Organized by KITECH, KIMM, Device Technology Institute/AIST, International Joint Laboratory For Micro/Nano Manufacturing And Measurement Technology, Xi'an Jiaotong University

14:00 Opening remarks (Chaired by Prof. Sung-ho Lee)

Prof Nakkyu Lee at KITECH, Prof. Masayoshi Esashi at Tohoku University, Prof Jiang at XJTU

Plenary session, Chairs (Dr. Eung-sug Lee)

14:10 Plenary Talk 1, "MEMS for aerosol measurements" Prof. Yong-Jun Kim, Yonsei University

14:35 Plenary Talk 2, "IEEE and Human Networks", Prof. Toshio Fukuda, IEEE President

15:00 Plenary Talk 3, "Success of iCAN", Prof. Haixia Zhang, Beijing University

15:25 Coffee Break

Invited session (Prof. Zhao Libo, Toshihiro Itoh)

15:40 Invited Talk1 "Transfer Printing based Heterogeneous material integration for novel sensor and device applications", Dr. Ho Hyun Keum/KITECH

16:00 Invited Talk2 "High-Sensitivity Nucleic Acid Screening for COVID-19 Solutions for Pooled Sample Testing" Ruobo Peng, project manager Xi'an Tianlong Science&Technology

16:20 Invited Talk3 "Non-contact manipulation in micro environment", Prof. Tsuo Arai, UEC(Univ. Electro-Communications)/ BIT

16:40 Invited Talk4 "Replication of pressure sensitive elastomer films with hair-like surface nanostructures", Kwan Oh KIM/KIMM

17:00 Invited Talk5 "MEMS-BASED FORCE SENSORS FOR VITAL SIGN MONITORING", Dr. Nguyen Thanh Vinh, AIST

17:20 Invited talk 6 "Printed Flexible Hybrid Electronics (FHE) for Sensors and Sensing Network", Dr. X. C. Shan, SIMTECH

17:40 Announcement of JCK MEMS/NEMS 2021 at Yantai(烟台), Prof. Libo Zhao

18:00 Short announcement of IEEE Sensors2024

18:30 Networking Banquet from Local points
